

# PATENT ABSTRACTS OF JAPAN

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(71)Applicant : SHIMADZU CORP

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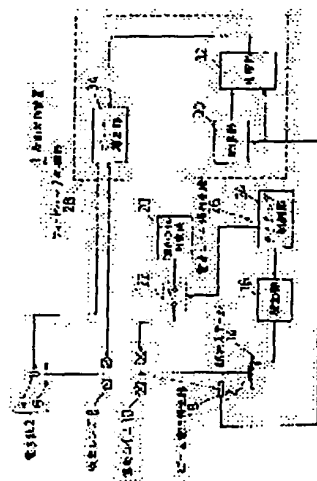
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## (54) SURFACE ANALYZER

### (57)Abstract:

**PURPOSE:** To invariably obtain analysis results with high reliability by utilizing the time of the backlash removing action of a sample stage to monitor the aging change of the radiation state of an electron beam and feedback-controlling the radiation state of the electron beam based on monitored results.

**CONSTITUTION:** An electron beam deflecting means 26 deflects an electron beam in coincidence with the timing of the backlash removing action of a sample stage 14 by a driving section 16. This deflected electron beam is detected by a beam current detecting section 18. A feedback control section 28 controls an electron gun 2 and a focusing lens 8 based on the detected output to correct the radiation state of the electron beam. The aging change of the radiation state of the electron beam is invariably corrected, thus analysis results with high reliability are invariably obtained.





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